

FILE COPY**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**In re application of:
Syun-Ming Jang, et al.

Serial No.: 09/086,772

Filed: May 29, 1998

For: Hard Masking Method for Forming
Patterned Oxygen Containing Plasma
Etchable Layer§
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Docket No.: 1997-0306/24061.603

Customer No. 42717

Group Art Unit: 1754

Examiner: Cam Nguyen

Conf. No.: N/A

TRANSMITTALCommissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Enclosed for filing in the above-identified patent application.

1. Revocation/New Power of Attorney by Assignee of Entire Interest
Including Certification for Taking Action by Assignee Under 37 CFR 3.73(b); and
2. Return Receipt Postcard

Applicant believes no fee is due. However, the Director is authorized to charge any deficiency fees or credit any overpayments to Deposit Account No. 08-1394 of Haynes and Boone, LLP.

Respectfully submitted,

David M. O'Dell
Reg. No. 42,044Date: January 7, 2005HAYNES AND BOONE, LLP
901 Main Street, Suite 3100
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Facsimile: 214-200-0853

Customer Number: 42717

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner For Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on the date indicated below:

Name

Kelly A. Moreau

Date

January 10, 2005

Customer No.: 42717

SCHEDULE A - Page 1 of 2

Docket No.	Applicant	Serial No.	Filing Date	Conf. No.	Assignment Recordation Date	Assignment Recordation Reel/Frame
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Customer No.: 42717

SCHEDULE A - Page 2 of 2

Docket No.	Applicant	Serial No.	Filing Date	Conf. No.	Assignment Recordation Date	Assignment Recordation Reel/Frame
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REDACTED

24061.603 (1997-0306)	Syun-Ming Jang, et al.	09/086,772	05-29-98	N/A	05-29-1998	09221/0364
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DESCRIPTION OF PAPER	The following were received in the U.S. Patent and Trademark Office on the date stamped hereon, via		
	First Class Mail: 1) Transmittal; 2) Revocation/New Power of Attorney by Assignee; and 3) this return receipt postcard		
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APPLICANT	Syun-Ming Jang, et al.		HAYNES and BOONE, LLP RICHARDSON
SERIAL NO.	09/086,772	DATE FILED	May 29, 1998
ATTORNEY DOCKET NO.	24061.603		
TITLE	Hard Masking Method for Forming Patterned Oxygen Containing Plasma Etchable Layer		
SENDER'S INITIALS	DMO/dh/kam48	DATE MAILED	1-10-2005